

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent No. 7,247,248 B2
Patent Issue Date July 24, 2007
Application Serial No. 10/516,927
Filing Date December 1, 2004
Assignee Sensfab Pte Ltd
Inventorship Tee et al.
Attorney's Docket No. DR10-006
Title: Method of Forming Atomic Force Microscope Tips

REQUEST FOR CERTIFICATE OF CORRECTION OF PATENT
FOR PTO MISTAKE (37 C.F.R. 1.322(a))

To: Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
ATTN: Decision and Certificate of Correction
Branch of the Patent Issue Division

From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)
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601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828

Sir/Madam:

It is hereby requested that a Certificate of Correction be issued with respect to Patent No. 7,247,248 B2, granted July 24, 2007, in accordance with the Certificate of Correction form attached hereto.

The error(s) listed on the Certificate of Correction form were apparently incurred through the fault of the PTO as will be disclosed by the records of files in the Office.

Attached hereto is Form PTO-1050 which is suitable for printing.

Since this Certificate of Correction is being requested due to PTO errors, it is believed that no fee is due. However, in the event that a fee is required for issuance of this Certificate of Correction, please charge the fee specified under 37 C.F.R. § 1.20(a) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Respectfully submitted,

Dated: 1/4/2008

By: Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

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CERTIFICATE OF CORRECTION

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PATENT NO. : 7,247,248 B2

APPLICATION NO.: 10/516,927

DATED : July 24, 2007

INVENTOR(S) : Tee et al.

It is certified that an error or errors appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 2, Line 56 – Replace “silicon I” with --silicon 1--.

Column 4, Line 27 – Replace “A method of...” with --A method of forming silicon atomic force microscope tips including the steps of:--.

Column 5, Line 22 – Replace “is and electrochemical” with --is an electrochemical--.

Mailing Address of Sender:

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